

# EUV ablation

**C. Liberatore<sup>1,2</sup>, A. Bartnik<sup>5</sup>, K. Mann<sup>4</sup>, M. Müller<sup>4</sup>, L. Pina<sup>2</sup>,  
L. Juha<sup>3</sup>, J. J. Rocca<sup>6</sup> , A. Endo<sup>1</sup>, T. Mocek<sup>1</sup>**

<sup>1</sup> Hilase Center, Dolni Brezany, Czech Republic

<sup>2</sup> Czech Technical University, Prague, Czech Republic

<sup>3</sup> Institute of Physics ASCR, Prague, Czech Republic

<sup>4</sup> Laser Laboratorium Göttingen (LLG), Göttingen, Germany

<sup>5</sup> Institute of Optoelectronics (IOE) ,Military University of Technology, Warsaw, Poland

<sup>6</sup> Department of Electrical and Computer Engineering, Colorado State University, Fort Collins, USA

*Neutral atoms or condensed matter cannot emit EUV radiation.*

**Ionization must take place first.**

***Electron transition produces photon of certain energy (EUV generation)***  
***Photon can be absorbed by ions (ionization)***

The processes of EUV generation and absorption (ionization) strongly compete against each other.



*The high demand to increase the density of circuit elements on microchips brought the standard technique for printing circuits patterns to its limit.*

*The development of a new method named extreme ultraviolet lithography (EUVL) is further connected with development of new types of high power extreme ultraviolet (EUV) lasers.*

*For the development of photoresist capable of simultaneously fulfill three main requirements related to sensitivity, resolution, and line edge.*

## Material of interest



## Polymers

Irradiation-induced solubility changes are due to the scission of either the main polymer chain or a sensitive dissolution inhibitor inside the material; both converts into a develop-soluble group upon exposition

## *Penetration*

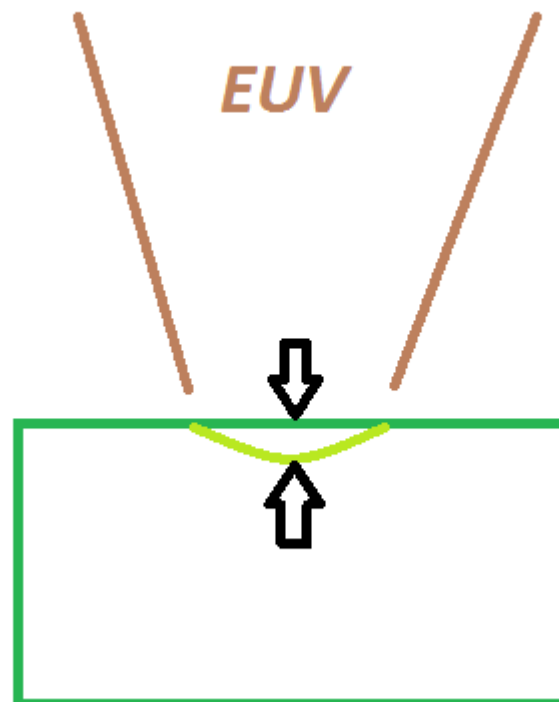


EUV are absorbed deeply  
in the matter with  
respect to current ablation

**Inverse bremsstrahlung  
Is inefficient**

short skin depth

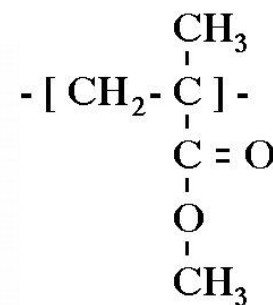
short penetration



Evaluate the advantages and disadvantages of experimental systems working at different wavelength with respect to the possibility to micro/nano structuring the polymers and as a guideline to build a more efficient EUV source



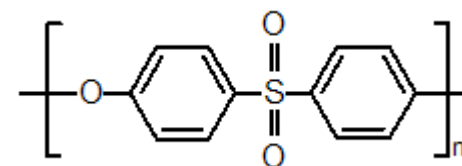
- Resistance,
- Surface recombination and nanostructuring,
- Chemical property.



PMMA

As a starting point we use PMMA.

We test the Poly(1,4-phenylene ether ether-sulfone).  $\longrightarrow$  Radiation resistance higher than PMMA.



Poly(1,4-phenylene ether ether-sulfone)



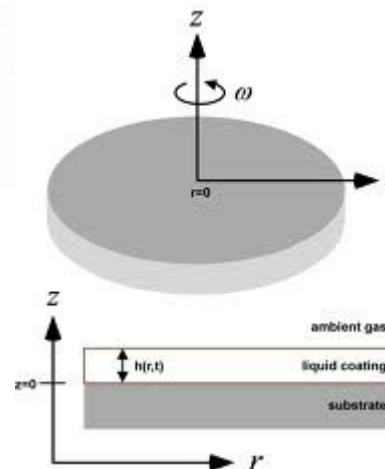
The Poly(1,4-phenylene ether ether-sulfone) target was prepared by a **spin coating** processes on a silicon substrate.

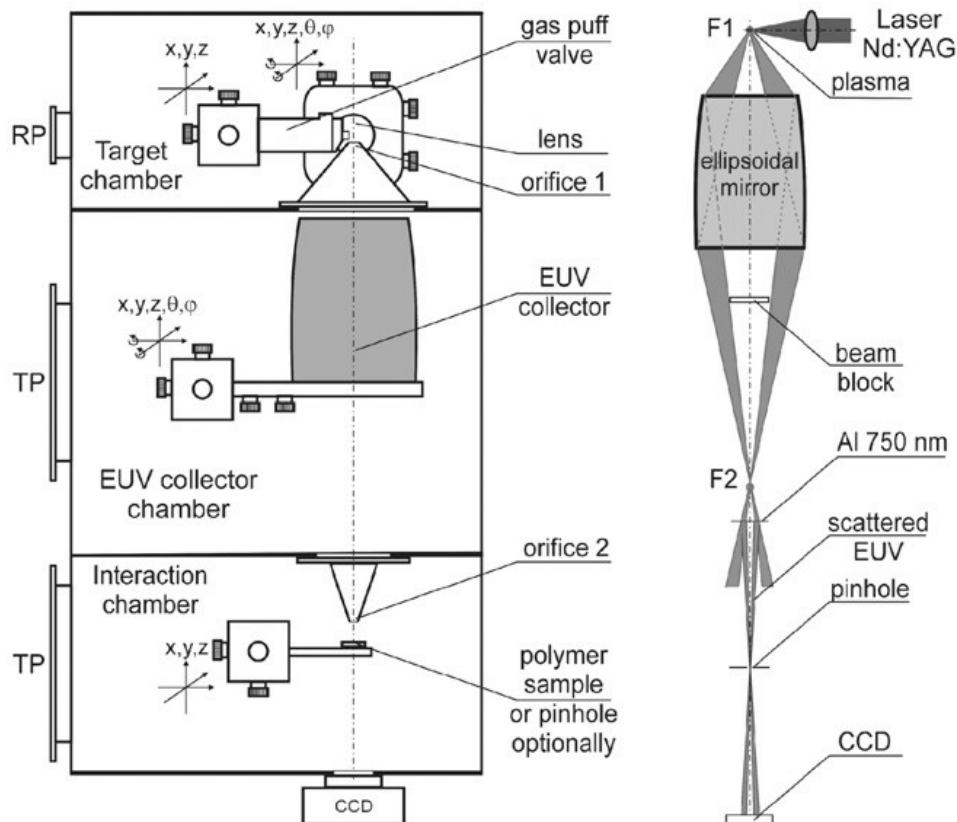
## Spin coating process

### Elements affecting the properties of coated films:

- Rotational speed;
- Acceleration;
- Fume exhaust .

**Critic Factor:**  
Repeatability.





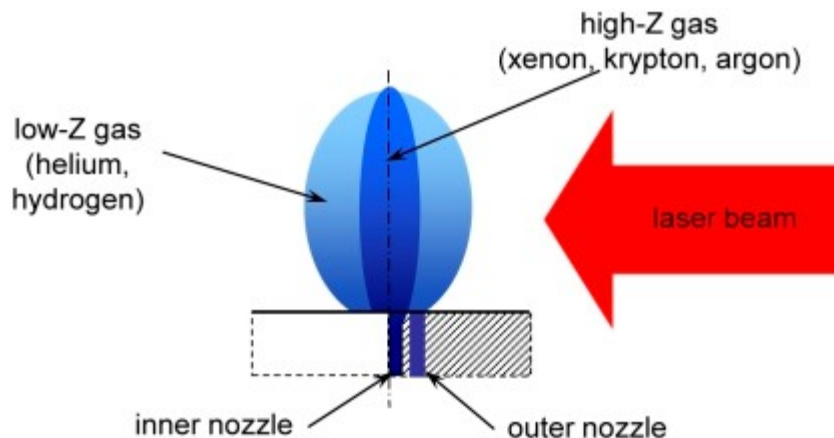


## Double stream gas puff target plasma source

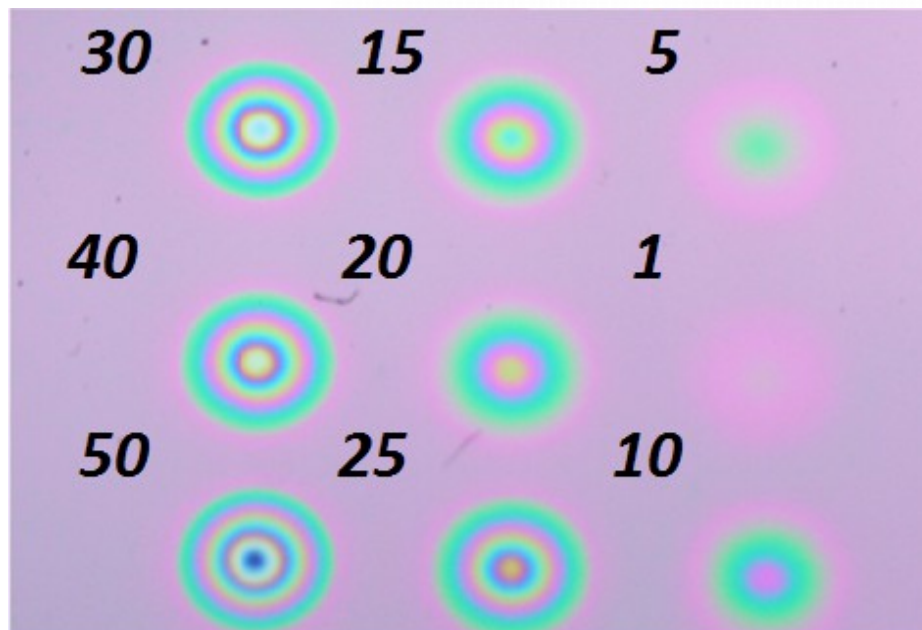
### Advantages:

- ✓ no debris from gaseous targets
- ✓ compact construction, high repeatability
- ✓ high conversion efficiency, very robust
- thousands of shots/day

Target = Xe-Kr mixture

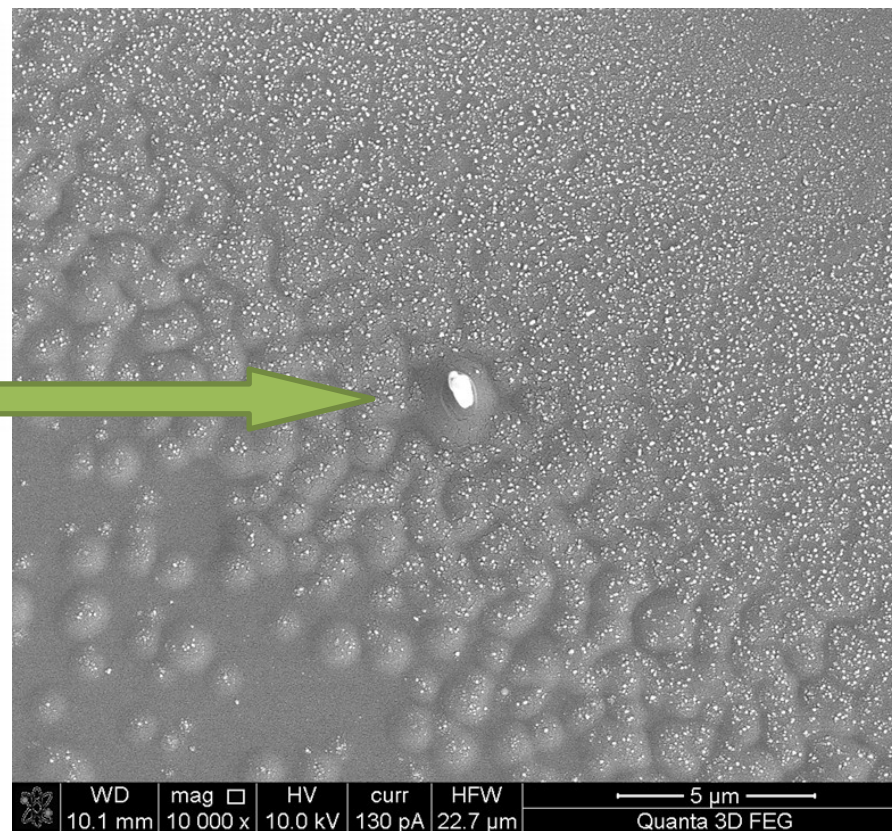


# Ablation test PPEES (WAT)

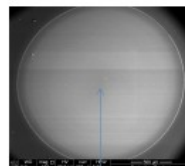


Gold coated target

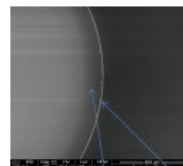
Conical structure



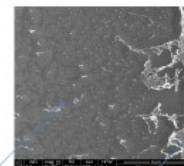
Polymer layer on Si plate irradiated with 50 EUV pulses



EDS spectrum No 1



EDS spectrum No 2



EDS spectrum No 3



EDS spectrum No 1

Only Si, polymer layer completely removed



EDS spectrum No 2

Si plus C, polymer layer partially removed



EDS spectrum No 3

Si plus C, polymer layer partially removed



The difference between the irradiated and not irradiated part, from the point of view of the material properties is not very deep.

Chemical properties of the material are preserved.



**CDL** (FROM PROF. j.j.Rocca, CU, USA)

**characteristics:**

**Dimensions:** 0.4 x 0.4 m<sup>2</sup> (0.4 x 0.8 m<sup>2</sup> with TM pump)

**Weight:** 400 kg

**Wavelength:** 46.9 nm

**Pulse length:** 1.5 ns (FWHM)

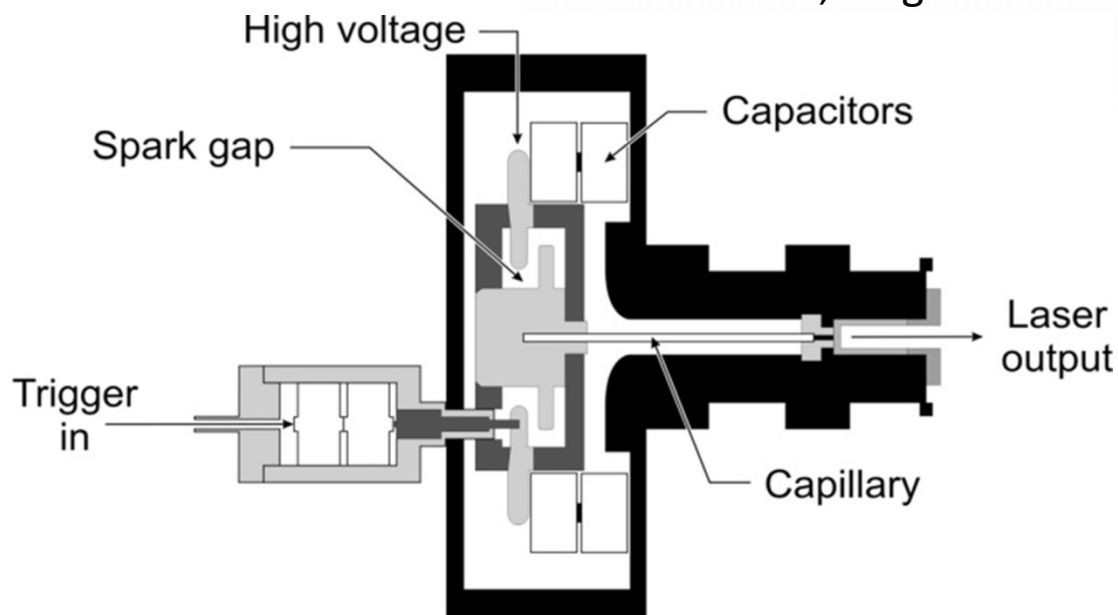
**Pulse energy:** > 10 mJ

**Repetition rate:** 5 Hz – typical, 12 Hz – maximum

**Capillary lifetime:** (2-3) x 10<sup>4</sup> pulses

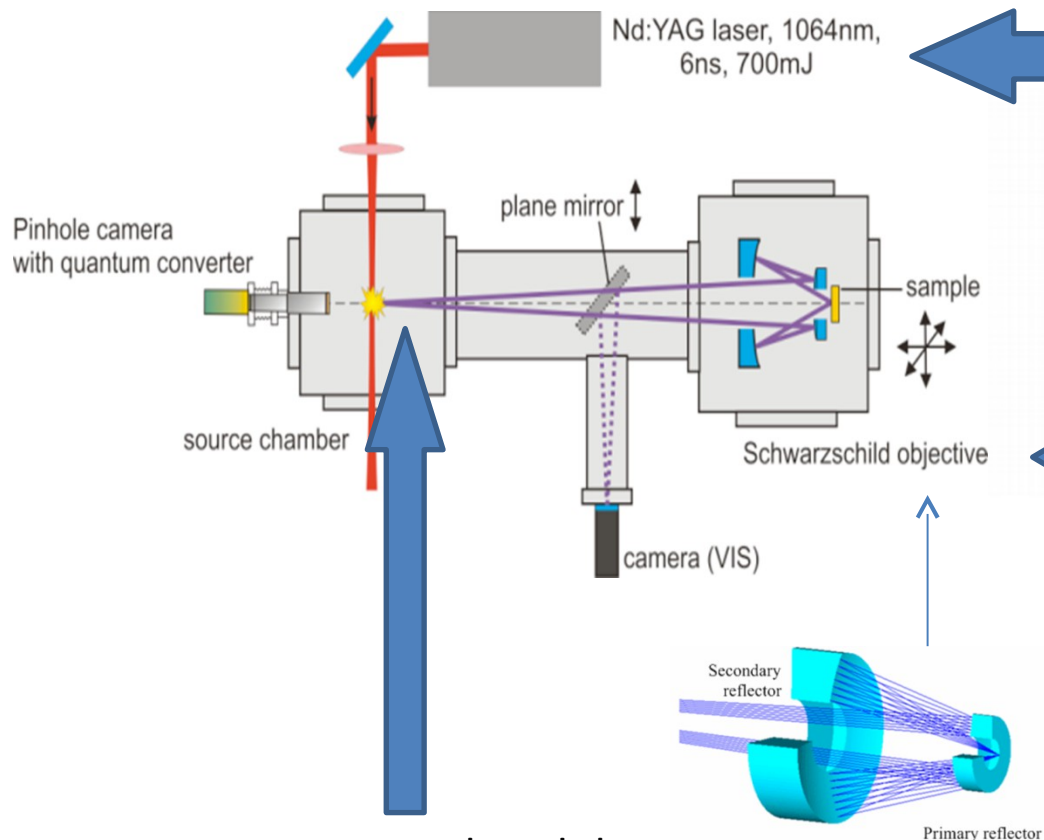
**Current:** ~21 kA

**Capillary:** Al<sub>2</sub>O<sub>3</sub> (inner diameter: 3.2 mm, length 210 mm), Ar filled (50 Pa)





# Experimental system at LLG

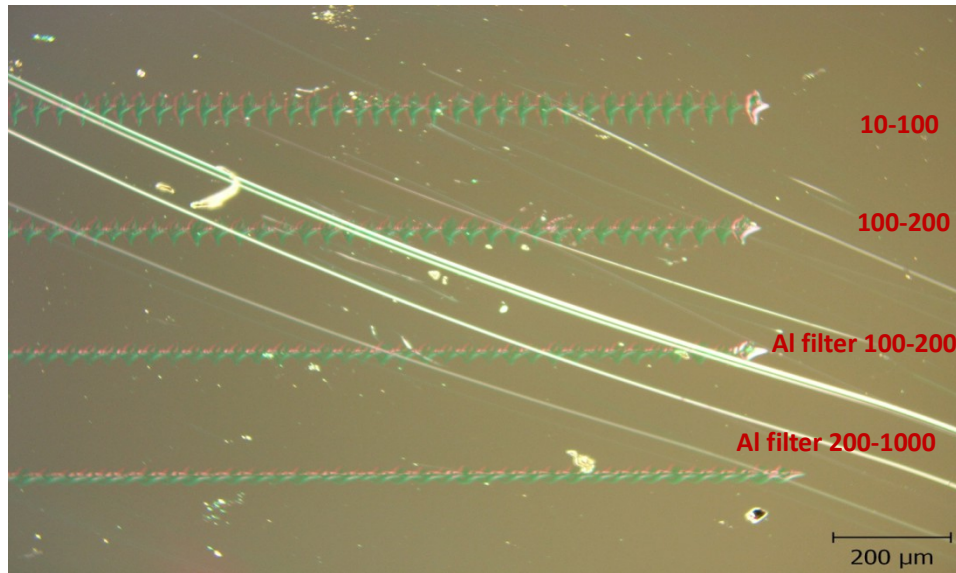


A Xenon target replaced the old gold one → avoid mechanical problem

A new laser (1200mJ) replaced the old one allowing to increase the fluence

A new Schwarzschild was inserted in the system.

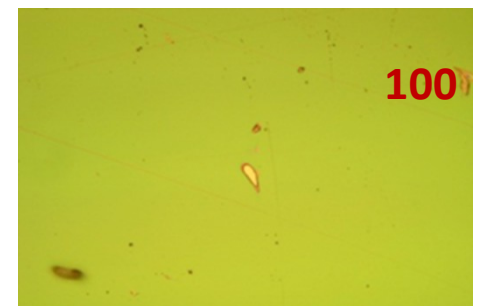
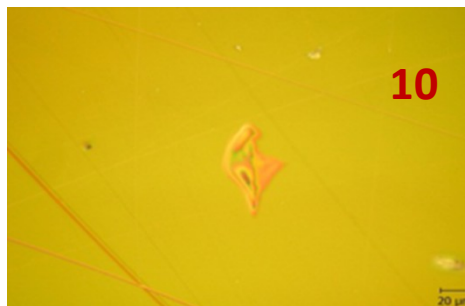
Characteristic:  
Modified design  
Mo/Si multilayer coating  
Peak wavelength 13.5nm ( $\pm 2\%BW$ )  
Imaging of plasma  
Micro-focus with high EUV fluence



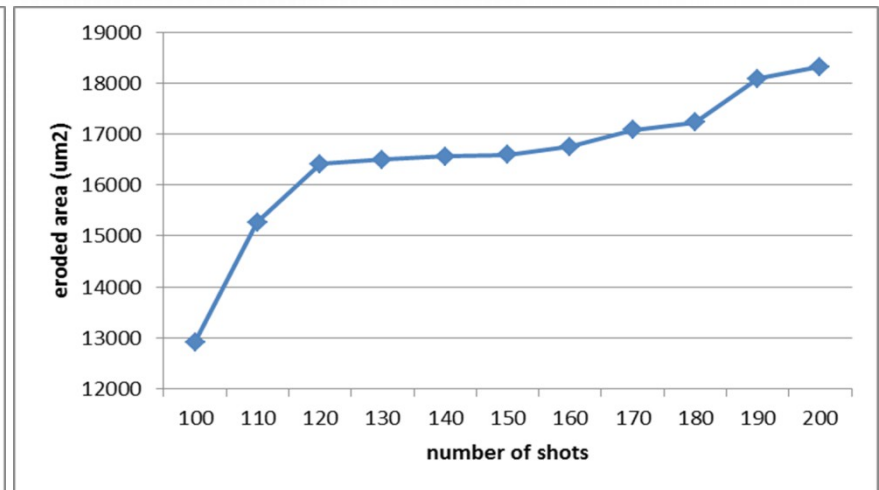
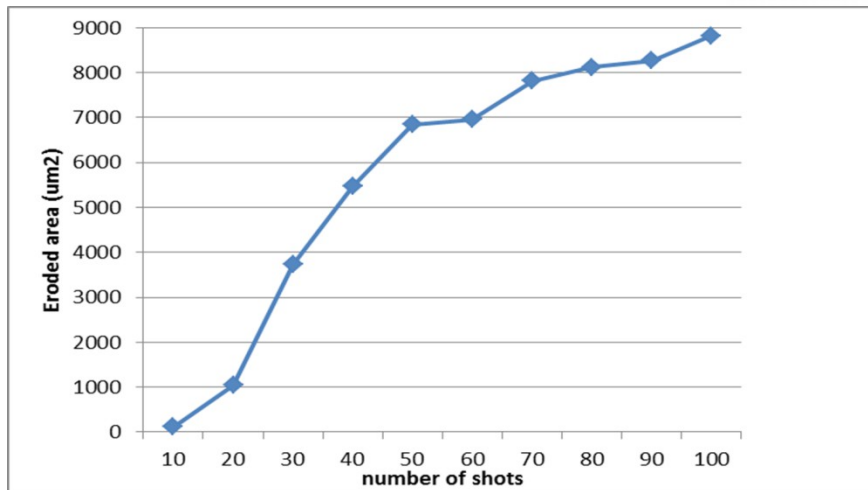
The possibility to ablate the poly (1,4 phenylene ether ether sulfone) by EUV was demonstrated.

The material has very high radiation resistance and, so, it's interesting for future medical and industrial application.

The crater structure is stable under number of shots variations and so, a well defined ablated area is selectable.

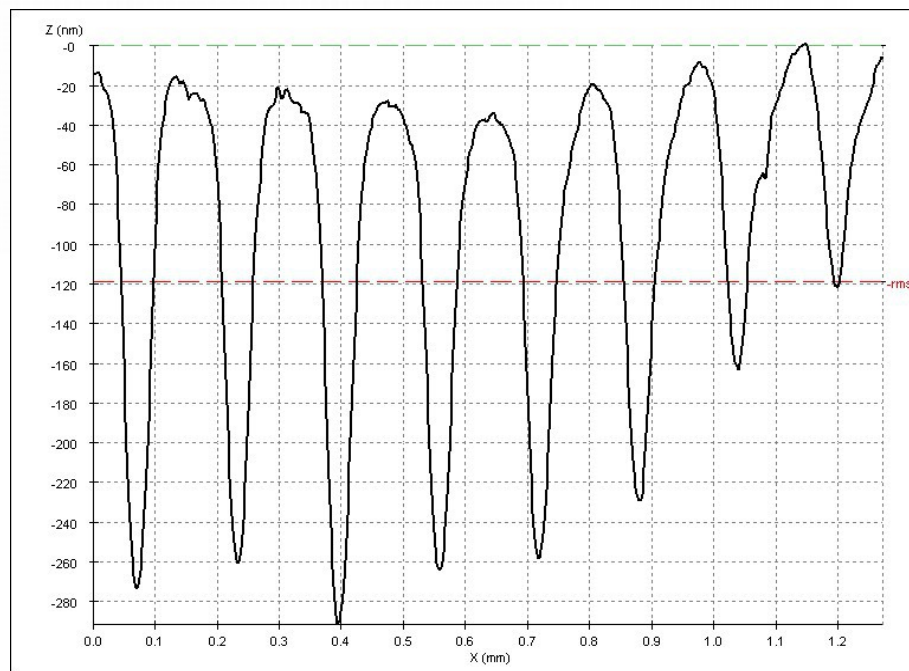
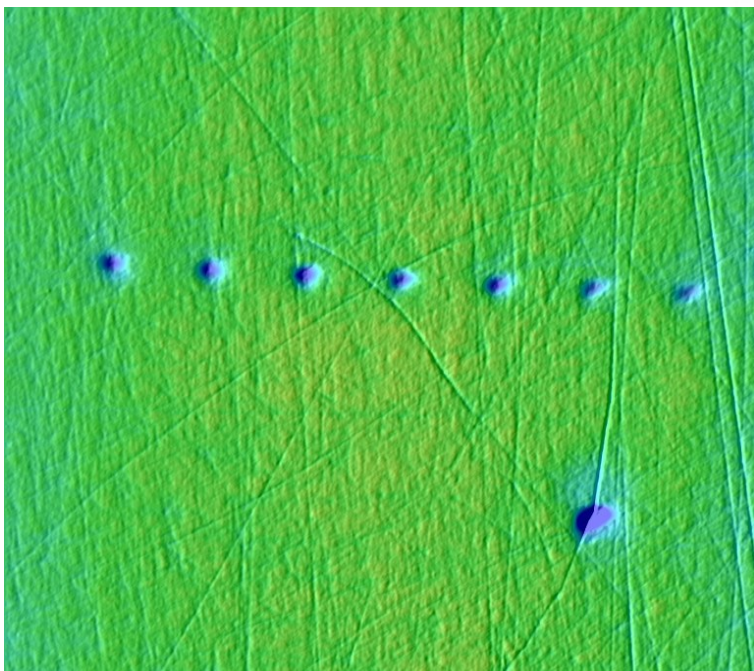


# PPEES: Eroded area/number of shots (Prague)

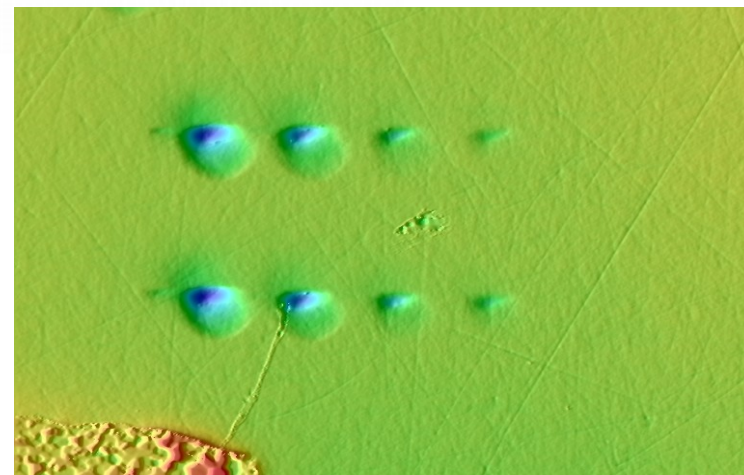
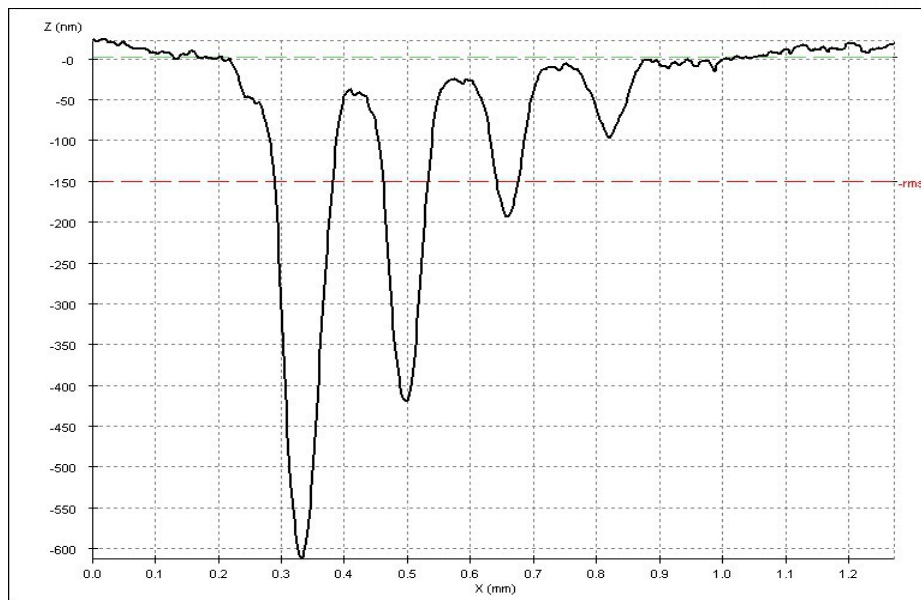


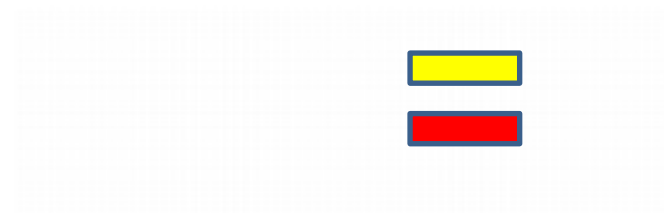


Caustic measurement on PMMA were performed to test the stability of the system and to find a good focal position.

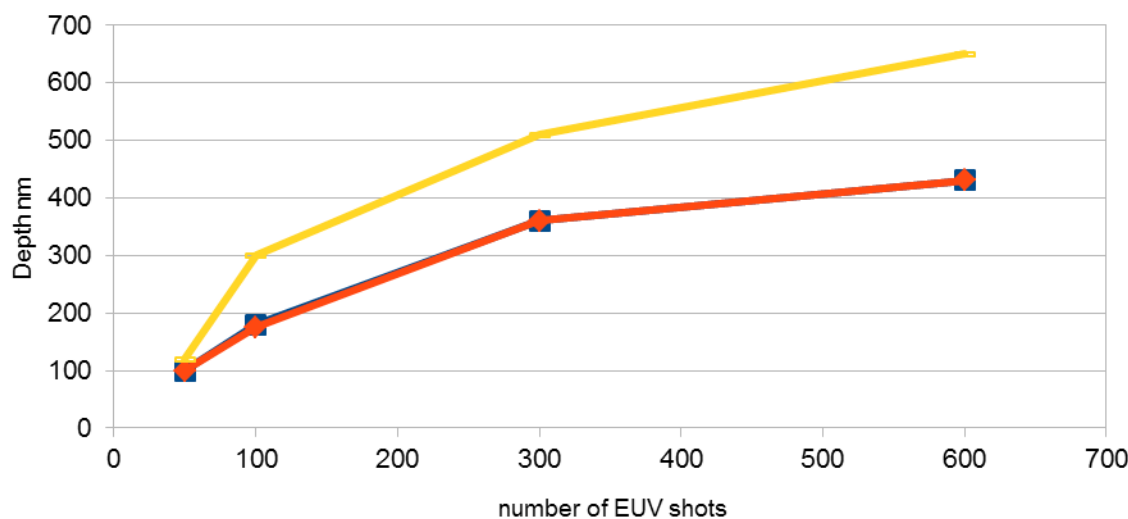


600 – 300 – 100 – 50 shots



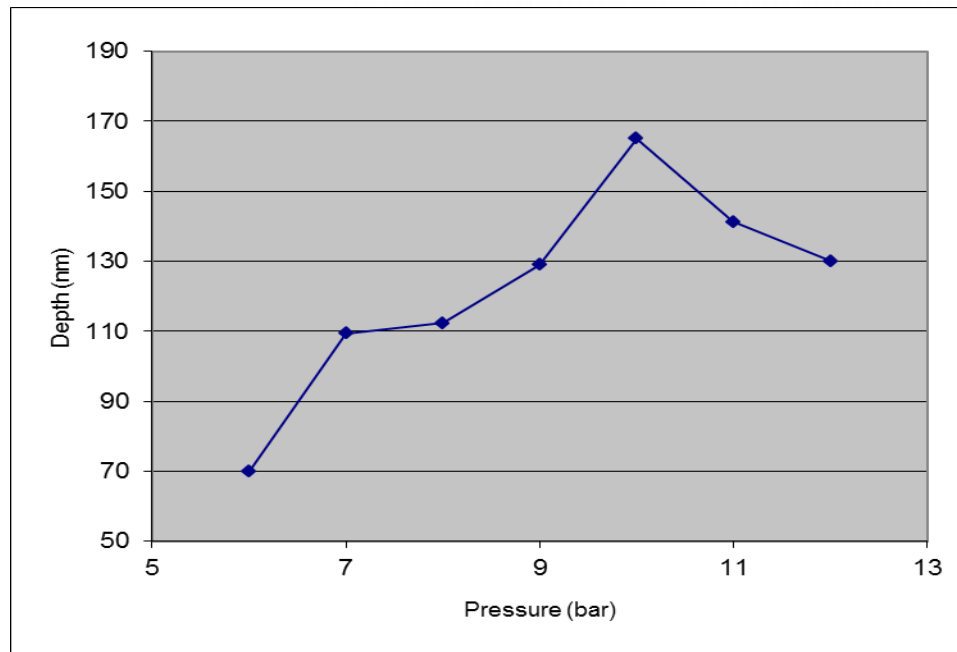


8 bar - 10 bar





The pressure at which the maximum depth is obtained is 10bar: the efficiency of the system is increasing with pressure till the re-absorbing process becomes dominant.



After focusing the focal position the working pressure 10 bar ablation tests were performed on:

- ❖ PEES;
- ❖ PI;
- ❖ Kapmon;
- ❖ Mylan.



All these materials have higher EUV radiation resistance than PMMA.

Ablation was not obtained because of too low fluence (limited by the laser and by the target used to produce the plasma).

Ablation test on PPEES was positive in Prague and negative at LLG

## Explanation

PPEES has a density of about 1.24 g/cm<sup>3</sup> and the following elemental composition C<sub>18</sub>SO<sub>4</sub>H<sub>12</sub>.

Its attenuation lengths at a wavelength of 13.5 nm (photon energy: 91.8 eV) is 215 nm.

Its attenuation length at a wavelength of 46.9 nm (photon energy: 26.4 eV) is approx. 20 nm.

## Conclusions:

- ❖ *at 46.9 nm the ablation threshold should be much lower than at 13.5 nm;*
- ❖ *during the exposure at 13.5 nm, the near surface region is not so "overexposed/overheated" as in the previous case (at 46.9 nm), so that single-photon radiolytical processes would play an important role in material ablation, making visible the difference in radiation stability of PPEES and PMMA.*

Ablation was obtained in Prague and in Warsaw's laboratories.

Some conditions are convenient to obtain EUV ablation:

- ❖ **Non monochromaticity;**
- ❖ **Long wavelength;**
  - ❖ **High fluence;**
- ❖ **High density target (to create the plasma).**



- [1] Bowden and O'Donnell 1985, Dev. Polym. Degrad, 6 (1985) 21-61
- [2] Schnabel, W. *Polymer Degradation: Principles and Practical Applications* Macmillan Publishing Co., Inc: New York, 1981, 139, 131-135, 146-148, 95-98,100, 133-137
- [3] F.S. Daintpn, K.J. Ivin, Proc. Roy Soc. (London) A212 (1952) 96-112, and 207-220
- [4] F. Barkusky, C. Peth, A. Bayer, K. Mann, Journal of Applied Physics 101 (2007) 124908
- [5] <http://www.clean.cise.columbia.edu/process/spintheory.pdf>
- [6] K. Mann, F. Barkusky, A. Bayer, J.O. Dette, S. Döring, B. Flöter, P. Grossmann, U. Leinhos, M. Lübbecke, M. Reese, M. Schöneck, B. Schäfer, Laboratory-scale EUV source for metrology and Studies on material interaction
- [7] Masud Mansuripur (July 1997) "The Ronchi test," *Optics & Photonics News*, vol. 8, pages 42-46
- [8] [www.smartcoater.com](http://www.smartcoater.com)



Dr Bartnik



Prof. Rocca



Dr Endo,  
Dr Mocek,  
Prof Pina



Laser-  
Laboratorium  
Göttingen e.V.

Prof Juha  
Mr Vysin

Dr Mann  
Mr Muller





# Thank you for your attention!

